

Christophe Gorecki

List of Publications by Year in descending order

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36
papers

457
citations

933447

10
h-index

839539

18
g-index

36
all docs

36
docs citations

36
times ranked

433
citing authors

#	ARTICLE	IF	CITATIONS
1	Fabrication of spherical microlenses by a combination of isotropic wet etching of silicon and molding techniques. <i>Optics Express</i> , 2009, 17, 6283.	3.4	103
2	AlN as an actuation material for MEMS applications. <i>Sensors and Actuators A: Physical</i> , 2008, 141, 565-576.	4.1	64
3	Effects of Amplitude and Phase Mismatching Errors in the Generation of a Kinoform for Pattern Recognition. <i>Japanese Journal of Applied Physics</i> , 1995, 34, 6423-6432.	1.5	46
4	Silicon-based integrated interferometer with phase modulation driven by surface acoustic waves. <i>Optics Letters</i> , 1997, 22, 1784.	3.3	40
5	A two directional electrostatic comb-drive X-Y micro-stage for MOEMS applications. <i>Sensors and Actuators A: Physical</i> , 2010, 163, 255-265.	4.1	38
6	Active microelement testing by interferometry using time-average and quasi-stroboscopic techniques. , 2003, 5145, 23.		31
7	Dense arrays of millimeter-sized glass lenses fabricated at wafer-level. <i>Optics Express</i> , 2015, 23, 11702.	3.4	25
8	Optimization of plasma-deposited silicon oxinitride films for optical channel waveguides. <i>Optics and Lasers in Engineering</i> , 2000, 33, 15-20.	3.8	20
9	Static and dynamic characterization of AlN-driven microcantilevers using optical interference microscopy. <i>Optics and Lasers in Engineering</i> , 2009, 47, 211-216.	3.8	13
10	Feedback-induced voltage change of a Vertical-Cavity Surface-Emitting Laser as an active detection system for miniature optical scanning probe microscopes. <i>Optics Express</i> , 2006, 14, 3396.	3.4	11
11	Fast ultra-deep silicon cavities: Toward isotropically etched spherical silicon molds using an ICP-DRIE. <i>Journal of Vacuum Science and Technology B: Nanotechnology and Microelectronics</i> , 2019, 37, 021206.	1.2	11
12	Micro-optical design of a three-dimensional microlens scanner for vertically integrated micro-opto-electro-mechanical systems. <i>Applied Optics</i> , 2015, 54, 6924.	2.1	7
13	Low cost production of computer-generated holograms: from design to optical evaluation. <i>Journal of the European Optical Society-Rapid Publications</i> , 0, 5, .	1.9	6
14	Simple method based on intensity measurements for characterization of aberrations from micro-optical components. <i>Applied Optics</i> , 2015, 54, 9060.	2.1	6
15	A micromachined silicon-based probe for a scanning near-field optical microscope on-chip. <i>Measurement Science and Technology</i> , 2006, 17, 32-37.	2.6	5
16	Characterization of internal stress of silicon oxinitride thin films fabricated by plasma-enhanced chemical vapor deposition: applications in integrated optics. , 2001, 4596, 9.		4
17	Towards integration of glass microlens with silicon comb-drive X-Y microstage. , 2008, , .		4
18	Matrixes of unconventional micro-optical components molded with etched silicon. <i>Journal of the European Optical Society-Rapid Publications</i> , 0, 5, .	1.9	4

#	ARTICLE	IF	CITATIONS
19	Miniature Schwarzschild objective as a micro-optical component free of main aberrations: concept, design, and first realization with silicon-glass micromachining. Applied Optics, 2016, 55, 2771.	2.1	4
20	Real-time pattern recognition by vanderlugt correlator using amplitude and phase modulation properties of the epon Liquid-Crystal TV. Optical Review, 1996, 3, 171-176.	2.0	3
21	Fabrication of 100% fill factor arrays of microlenses from silicon molds. Proceedings of SPIE, 2012, , .	0.8	3
22	Technological Platform for Vertical Multi-Wafer Integration of Microscanners and Micro-Optical Components. Micromachines, 2019, 10, 185.	2.9	3
23	Simple setup for optical characterization of microlenses. Proceedings of SPIE, 2014, , .	0.8	2
24	<title>Novel architecture for silicon-based integrated interferometer with phase modulation by elasto-optic effect</title>. , 1997, 3008, 152.		1
25	<title>Optical interferometry investigation of internal stress and optomechanical characteristics of silicon-oxynitride thin films fabricated by PECVD</title>. , 2002, , .		1
26	Topography measurements of high NA aspherical microlenses by digital holographic microscopy with spherical illumination. Proceedings of SPIE, 2017, , .	0.8	1
27	Design of a micro-optical low coherent interferometer array for the characterisation of MEMS and MOEMS. , 2009, , 1-7.		1
28	<title>Optimization of plasma-deposited silicon oxinitride films for interferometric MOEMS applications</title>. , 2000, , .		0
29	Interferometry system for the mechanical characterization of membranes with silicon oxynitride thin films fabricated by PECVD. , 2003, , .		0
30	Reliability study of AlN-driven microcantilevers based on interferometric measurements of their static and dynamic behaviours. , 2010, , .		0
31	Integrated glass lenses fabrication for parallel interferometric inspection systems of MEMS and MOEMS. Proceedings of SPIE, 2010, , .	0.8	0
32	Level set method for microfabrication simulations. , 2010, , .		0
33	Determination of failure mechanisms for AlN-based microcantilevers with use of Twyman-Green interferometry. , 2012, , .		0
34	Interferometry of AlN-based microcantilevers to determine the material properties and failure mechanisms. , 2012, , .		0
35	Metrology of micro-optical components quality using direct measurement of 3D intensity point spread function. , 2014, , .		0
36	Microsystem based optical measurement systems: case of opto-mechanical sensors. , 2006, , 597-604.		0